

Amendments to the Specification:

Please replace the paragraph beginning at page 7, line 13, with the following paragraph:

--The optical system 16 is intended to create a relatively small spot on the sample surface. For semiconductor applications, the spot size can be less than 5mm, should be less than 3mm, and is preferably about 1.5 mm in diameter. In the illustrated embodiment, the system will actually create two spatially separate spots of different polarization states. This is because the polarizer 14 is a Rochon prism which causes one polarization to be angularly deviated with respect to the other polarization such that two separate beams are created. Each beam is focused at a spatially separate spot on the sample. --

Please replace the paragraph beginning at page 2, line 6, with the following paragraph:

--Due to these difficulties, researchers in the prior art began using curved mirrors to focus the broadband probe beam onto the sample surface. Mirrors are advantageous since they can be highly reflective across a broad range of wavelengths. In addition, mirrors exhibit little or no chromatic aberrations. The use of focusing mirrors for a broadband ellipsometer are described in U.S. Patents patents, No. 4,790,659, issued December 1988, to Erhman, and No. 5,608,526, issued March 4, 1997, to Piwonka-Corle.--

Please replace the paragraph beginning at page 4, line 29, with the following paragraph:

-- The basic operation of the subject ellipsometer is similar to other broadband ellipsometers and need not be discussed herein. Further information can be obtained from prior patents and applications: U.S. Patent 5,877,859 to Aspnes et al.; U.S. Patent 5,608,526 to Piwonka-Corle et al.; and WIPO Application WO99/02970 to Rosencwaig et al., all incorporated herein by reference. As can be seen, there are a number of variations in light sources and beam detection (spectrometer) systems. In addition, there are a number of approaches possible for extracting ellipsometric information including rotating polarizers, analyzers and compensators. These elements can be continuously rotated or indexed. In addition, the ellipsometer can be operated as a nulling ellipsometer. The subject invention is intended to be applied to any of these embodiments all of which are well known and understood by those skilled in the art. --